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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.		
09/677,805	10/02/2000	William Bedingham	55943 USA 1A	3624		
32692 7:	590 03/08/2004		EXAM	EXAMINER		
3M INNOVA	TIVE PROPERTIES CO	GORDON,	GORDON, BRIAN R			
PO BOX 33427 ST. PAUL, MI		ART UNIT	PAPER NUMBER			
51.1AOL, WIV 33133 3127			1743			
			DATE MAILED: 03/08/2004			

Please find below and/or attached an Office communication concerning this application or proceeding.

		Applicati	on No.	Applicant(s)	<i>t</i> t
		09/677,86	05	BEDINGHAM ET AL.	
	Office Action Summary	Examine	-	Art Unit	
		Brian R.		1743	
Period fo	The MAILING DATE of this communi or Reply	ication appears on the	e cover sheet with the c	orrespondence ad	ldress
THE - Exte after - If the - If NC - Failu Any	ORTENED STATUTORY PERIOD FOR MAILING DATE OF THIS COMMUNI- nsions of time may be available under the provisions SIX (6) MONTHS from the mailing date of this comm is period for reply specified above is less than thirty (30) period for reply is specified above, the maximum state the to reply within the set or extended period for reply reply received by the Office later than three months at ed patent term adjustment. See 37 CFR 1.704(b).	CATION. of 37 CFR 1.136(a). In no ev unication. o) days, a reply within the stat tutory period will apply and w will, by statute, cause the app	ent, however, may a reply be tim utory minimum of thirty (30) day ill expire SIX (6) MONTHS from lication to become ABANDONE	nely filed s will be considered timel the mailing date of this c D (35 U.S.C. § 133).	
Status					
· · · · · · · · · · · · · · · · · · ·	Responsive to communication(s) file This action is <b>FINAL</b> .  Since this application is in condition to closed in accordance with the practic	2b)⊠ This action is r for allowance except	for formal matters, pro		e merits is
Dispositi	ion of Claims				
5)⊠ 6)⊠ 7)⊠	Claim(s) 6-8,13 and 16-49 is/are per 4a) Of the above claim(s) is/are Claim(s) 21-43 is/are allowed. Claim(s) 6,13,16,20 and 44 is/are rej Claim(s) 7,8,17-19,45-49 is/are object to restrice	re withdrawn from co ected. ected to.	nsideration.		
Applicati	ion Papers				
10)	The specification is objected to by the The drawing(s) filed on is/are: Applicant may not request that any object Replacement drawing sheet(s) including The oath or declaration is objected to	a) accepted or b) stion to the drawing(s) the correction is require	be held in abeyance. See ed if the drawing(s) is obj	e 37 CFR 1.85(a). jected to. See 37 Cl	` ,
Priority (	under 35 U.S.C. § 119				
a)(	Acknowledgment is made of a claim for the priority of the certified copies of the certified copies of the priority of the prio	documents have bee documents have bee of the priority documental Bureau (PCT Rul	en received. En received in Applicati ents have been receive e 17.2(a)).	on No ed in this National	Stage
2) Notice 3) Information	et(s)  Dee of References Cited (PTO-892)  Dee of Draftsperson's Patent Drawing Review (Pomation Disclosure Statement(s) (PTO-1449 or the No(s)/Mail Date		4) Interview Summary Paper No(s)/Mail Da 5) Notice of Informal P 6) Other:	ate. <u>3-1-04; 2-9-04</u> .	O-152)

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#### **DETAILED ACTION**

### Response to Amendment

Applicant's request for reconsideration of the finality of the rejection of the last
 Office action is persuasive and, therefore, the finality of that action is withdrawn.

### Response to Arguments

2. Applicant's arguments with respect to claims 6, 13, 16, and 20 have been considered but are most in view of the new ground(s) of rejection.

### Claim Rejections - 35 USC § 112

- 3. The following is a quotation of the second paragraph of 35 U.S.C. 112:
  The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.
- 4. Claims 6, 13, 16, 20, and 44 rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

Claims 6, 13, 16, 20, and 44 recite an apparatus for processing sample materials; however, the claims do not clearly indicate where and how the sample is processed. Is the sample processed by in one of the filter material, in the fluid chambers, in the retention structure, and the multi-chambered processing device or all of the above?

It appears as if applicant's device comprises two-types of stationary chambers with the plurality of stationary fluid chambers that are present in the platform. A first set of chambers that actually holds the sample to processed in the processing device and a second set that contains filters for filtering the processed samples. As presently drafted,

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the claims do clearly express this arrangement of the invention. As presently drafted, the claims do not particularly point out the relationship and function the elements in reference to the sample materials.

- 5. The following claims drafted by the examiner and considered to distinguish patentably over the art of record in this application, were presented to applicant for consideration:
- 6. An apparatus for processing sample materials, the apparatus comprising: a platform comprising an upper surface and a lower surface; a plurality of stationary fluid chambers opening at the upper surface of the platform; wherein at least some of said plurality of stationary fluid chambers further comprise sample material to be processed and at least some of said stationary fluid chambers comprise filter material for filtering a
- at least some of said stationary fluid chambers comprise filter material for filtering a processed sample;
- a rotating, multi-chambered processing device;
- <u>a</u> retention structure occupying a portion of the upper surface of the platform, wherein the retention structure is capable of retaining said rotation multi-chambered processing device:
- wherein said sample is processed within the rotating multi-chambered processing device.
- 13 An apparatus for processing sample materials, the apparatus comprising: a platform comprising an upper surface and a lower surface; a plurality of stationary fluid chambers opening at the upper surface of the platform; wherein the plurality of stationary fluid chambers are arranged in rectilinear array on the upper surface of the platform and at least some of said stationary fluid chambers further comprise sample material to be processed; and a retention structure occupying a portion of the upper surface of the platform; and a processing device located within the retention structure proximate the upper surface of the platform, the processing device comprising a plurality of process chambers wherein the processing device is capable of being rotated within the retention structure to rotate the plurality of process chambers in order to process said sample material and ...(the rest of the claim as presented).
- 16. An apparatus for processing sample materials, the apparatus comprising: a platform comprising an upper surface and a lower surface; a plurality of stationary fluid chambers opening at the upper surface of the platform;

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wherein at least some of said plurality of stationary fluid chambers further comprise sample material to be processed and

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at least some of said stationary fluid chambers comprise filter material <u>for filtering a processed sample</u>;

<u>a</u> retention structure occupying a portion of the upper surface of the platform; and a processing device located within the retention structure proximate the upper surface of the platform, the processing device comprising a plurality of process chambers wherein the processing device comprises a plurality of process chambers, wherein the processing device is capable of being rotated within the retention structure to <u>rotate</u> the plurality of process chambers <u>in order to process said sample material.</u>

- 20. An apparatus for processing sample materials, the apparatus comprising: a platform comprising an upper surface and a lower surface; a plurality of stationary fluid chambers opening at the upper surface of the platform; wherein at least some of said plurality of stationary fluid chambers further comprise sample material to be processed
- <u>a</u> retention structure occupying a portion of the upper surface of the platform; a processing device located within the retention structure proximate the upper surface of the platform, the processing device comprising a plurality of process chambers wherein the processing device comprises a plurality of process chambers, wherein the processing device is capable of being rotated within the retention structure to <u>rotate</u> the plurality of process chambers <u>in order to process said sample material</u>, wherein the processing device is captive within the retention structure.

In claim 44, line 7 add the phrase to process said sample material, so as to read "noves the plurality of process chambers in a circular pattern to process said sample material;

Applicant refused the above amendment and declined to present any proposed amendments that would also obviate the above 112 issues.

## Allowable Subject Matter

- 6. Claims 21-43 allowed.
- 7. Claims 6, 13, 16, 20, and 44 would be allowable if rewritten or amended to overcome the rejection(s) under 35 U.S.C. 112, second paragraph, set forth in this Office action.

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rejection(s) under 35 U.S.C. 112, second paragraph, set forth in this Office action and to

Claims 7-8, 17-19, and 45-49 would be allowable if rewritten to overcome the

include all of the limitations of the base claim and any intervening claims.

9. The following is a statement of reasons for the indication of allowable subject

matter: see previous office action.

Conclusion

Any inquiry concerning this communication or earlier communications from the

examiner should be directed to Brian R. Gordon whose telephone number is 571-272-

1258. The examiner can normally be reached on M-F, with 2nd and 4th F off.

If attempts to reach the examiner by telephone are unsuccessful, the examiners

supervisor, Jill Warden can be reached on 571-272-1267. The fax phone number for

the organization where this application or proceeding is assigned is 703-872-9306.

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brg

/Jill Warden
Supervisory Patent Examiner